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**INFORMATION DISCLOSURE
 STATEMENT BY APPLICANT**
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Complete If Known

Application Number	10/081,818
Filing Date	February 20, 2002
First Named Inventor	Eldridge, Jerome
Group Art Unit	2818
Examiner Name	Ho, Tu-Tu

Sheet 1 of 8

Attorney Docket No: 1303.045US1

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Application Number	10/081,818
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Sheet 2 of 8

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Group Art Unit	2818
Examiner Name	Ho, Tu-Tu

Sheet 3 of 8

Attorney Docket No: 1303.045US1

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EXAMINER

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Substitute Disclosure Statement Form (PTO 1449)

* EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 606. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant. Applicant's unique citation designation number (optional) * Applicant is to place a check mark here if English language translation is attached

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First Named Inventor	Eldridge, Jerome
Group Art Unit	2818
Examiner Name	Ho, Tu-Tu

Sheet 4 of 8

Attorney Docket No: 1303.045US1

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Complete if Known

Application Number	10/081,818
Filing Date	February 20, 2002
First Named Inventor	Eldridge, Jerome
Group Art Unit	2818
Examiner Name	Ho, Tu-Tu

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Attorney Docket No: 1303.045US1

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